

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Venkat Selvamanickam, et al.

Title: APPARATUS FOR AND METHOD OF CONTINUOUS HTS TAPE
BUFFER LAYER DEPOSITION USING LARGE SCALE ION BEAM
ASSISTED DEPOSITION

App. No.: 10/609,250 Filed: June 26, 2003

Examiner: Ram N. Kackar Group Art Unit: 1763

Customer No.: 34456 Confirmation No.: 7760

Atty. Dkt. No.: 1014-SP101-US

MS AMENDMENT

Commissioner for Patents

PO Box 1450

Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Office Action mailed September 5, 2007, please amend the
above-identified application as follows: